

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANT:

Gormley et al.

GROUP:

2811

SERIAL NO:

09/661,766

EXAMINER: Hung K. Vu

FILED:

September 14, 2000

FOR:

A METHOD FOR FORMING A SEMICONDUCTOR DEVICE AND A

SEMICONDUCTOR DEVICE FORMED BY THE METHOD

Assistant Commissioner of Patents Washington, D.C. 20231 **Box Non-Fee Amendment**

Sir:

ant Commissioner of Patents
Ington, D.C. 20231

On-Fee Amendment

AMENDMENT

In response to the Office Action mailed November 11, 2002, please amend the above-identified application as follows:

IN THE CLAIMS

Please amend the claims as follows:

- 1. (Amended) A method for forming a semiconductor device comprising first, second 1
- and third layers, with a component being formed in the second layer, and first and second 2
- etch stop layers being located between the first and second layers, and the second and 3
- third layers, respectively, and at least the second etch stop layer being bonded to one of 4
- the second and third layers, the method comprising the steps of: 5
- prior to bonding the second etch stop layer to the one of the second and third 6
- layers, patterning the second etch stop layer to define the component in the second layer 7
- for facilitating etching of the second layer through the third layer, 8
- bonding the second etch stop layer to the one of the second and third layers, and 9